

Form PTO-1449 INFORMATION DISCLOSURE CITATION IN AN APPLICATION <i>(Use several sheets if necessary)</i>				Docket Number (Optional) 3579.2US (98-0062.02/US)		Application Number N t Y t Assigned	
				Applicant Dapeng Wang			
				Filing Date December 5, 2003		Group Art Unit Unknown	

U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
BR	5,232,875	08/1993	Tuttle et al.			
	5,514,245	05/1996	Doan et al.			
	5,624,299	04/1997	Shendon			
	5,664,989	09/1997	Nakata et al.			
	5,692,947	12/1997	Talieh et al.			
BR	5,692,950	12/1997	Rutherford et al.			

FOREIGN PATENT DOCUMENTS							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO
BR	57023965 A	02/1982	JP				
BR	58045861 A	03/1983	JP				

OTHER DOCUMENTS		(Including Author, Title, Date, Pertinent Pages, Etc.)
BR		Wang et al., <u>Von Mises Stress in Chemical-Mechanical Polishing Processes</u> , J. Electrochem. Soc., Vol. 144, No. 3, March 1997 pp. 1121-27.

EXAMINER 	DATE CONSIDERED 05/18/05
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.